International Conference on Space Optics—ICSO 2000

Toulouse Labège, France

5–7 December 2000

Edited by George Otrio

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International Conference on Space Optics — ICSO 2000, edited by George Otrio, Proc. of SPIE Vol. 10569 105691J · © 2000 ESA and CNES · CCC code: 0277-786X/17/\$18 · doi: 10.1117/12.2307927

Proc. of SPIE Vol. 10569 105691J-1

COMPUTER ASSISTED ASPHERICAL POLISHING : ADVANTAGES AND LIMITS

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SESO has increased by an important factor its capabilities of aspherical polishing with the technology of computer assisted polishing. The advantages and current limitations of this technology will be discussed :

- New performances obtained in terms of wavefront accuracy, mid-spatial-frequency errors, roughness,
- Capabilities to polish aspherical surface with low F number,
- The link to metrology development which is a critical part of polishing performances.